

Docket No.: APPM/008244US/DSM/BCVD/JW  
1016.014014  
(PATENT)

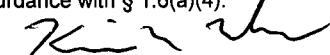
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Ling Chen, et al. §  
§  
Serial No.: 10/799,146 § Group Art Unit: 2893  
§  
Confirmation No.: 7933 § Examiner: M. D. Harrison  
§  
Filed: March 12, 2004 §  
§  
For: METHOD OF DEPOSITING AN §  
AMORPHOUS CARBON FILM §  
FOR ETCH HARDMASK §  
APPLICATION §  
MAIL STOP AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
Dear Sir:

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being transmitted via the Office electronic filing system in accordance with § 1.6(a)(4).

6/11/09

Date



(Keith M. Tackett)

**STATEMENT OF COMMON OWNERSHIP**

The present application Serial No. 10/799,146 (hereinafter the "Application") and U.S. Patent No. 6,853,043 to Yeh, et al. were, at the time the invention of the Application was made, owned by, or subject to an obligation of assignment to, Applied Materials, Inc., of Santa Clara, California.

Respectfully submitted,



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